



<b>Session Title:</b>	<b>[TuG2] Frontier Metrology and Modeling II</b>
<b>Session Date:</b>	<b>November 12 (Tue.), 2024</b>
<b>Session Time:</b>	<b>15:00-17:00</b>
<b>Session Room:</b>	<b>Room G (Meeting Room, 5F, Grand Josun Busan)</b>
<b>Session Chair:</b>	<b>Prof. Tae-Hun Shim (Hanyang Univ., Korea)</b>

**[TuG2-1] [Invited] 15:00-15:30**

**Bridging the Gap: From Surface Topography to Semiconductor Applications with ISE and AFM**

Dang Quang Nquyen, Geonwoo Kim, Seungmin Park, Mangesh Diware, and Sang-Joon Cho  
(Park Systems Corp., Korea)

**[TuG2-2] [Invited] 15:30-16:00**

**Multiscale Simulation and AI-Driven Approaches for Comprehensive Understanding of Advanced Materials and Semiconductor Processing**

Sung Beom Cho (Ajou Univ., Korea)

**[TuG2-3] [Invited] 16:00-16:30**

**Recent Progress of Display and Semiconductor Inspection Using FSH (Flying-over Scanning Holography)**

Taegeun Kim (Cubixel Co., Ltd., Korea)

**[TuG2-4] [Invited] 16:30-17:00**

**Nanoscale and Interfacial Physical Characterization for Supporting Memory Device Manufacturing**

Jae-Hyun Kim (SK hynix Inc., Korea)